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File: USPT

Jun 22, 2004

US-PAT-NO: 6754679

DOCUMENT-IDENTIFIER: US 6754679 B2

TITLE: Computer system with a plurality of database management systems

DATE-ISSUED: June 22, 2004

INVENTOR-INFORMATION:

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ASSIGNEE-INFORMATION:

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COUNTRY	APPL-NO	APPL-DATE
JP	2000-115782	April 11, 2000

INT-CL: [07] G06 F 17/30

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US-CL-CURRENT: 707/201; 707/10, 707/102, 707/2, 707/205, 709/232, 709/249, 719/313

FIELD-OF-SEARCH: 707/102, 707/104, 707/9, 707/10, 707/201, 707/200, 707/2, 707/205, 709/313, 709/249, 709/103, 709/104, 709/219, 709/232

PRIOR-ART-DISCLOSED:

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ART-UNIT: 2172

PRIMARY-EXAMINER: Corrielus; Jean M.

ATTY-AGENT-FIRM: Townsend and Townsend and Crew LLP

ABSTRACT:

According to the invention, a database combining module, such as a software on a server, is used together with a resource manager software of a disk storage system in which a database is stored. A resource allocation for the disk storage system is determined to satisfy specifications requested by a user provided to a database combining module. Host paths and volumes are allocated and snapshots are controlled based on the processing of these software modules.

17 Claims, 7 Drawing figures

Full	Title	Citation	Front	Review	Classification	Date	Reference	Abstract	Claims	KWC	Draw Desc	Image
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